

Handwritten signature/initials



Docket No.: 55071-267

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of	:	Customer Number: 20277
	:	
Stephen Duan-Fu HSU, et al.	:	Confirmation Number: 9799
	:	
Serial No.: 10/626,858	:	Group Art Unit:
	:	
Filed: July 25, 2003	:	Examiner:
	:	
For: ORIENTATION DEPENDENT SHIELDING FOR USE WITH DIPOLE ILLUMINATION TECHNIQUES		

INFORMATION DISCLOSURE STATEMENT

Mail Stop IDS
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In accordance with the provisions of 37 C.F.R. 1.56, 1.97 and 1.98, the attention of the Patent and Trademark Office is hereby directed to the references listed on the attached form PTO-1449. It is respectfully requested that the references be expressly considered during the prosecution of this application, and that the references be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

This Information Disclosure Statement is being filed within three months of the U.S. filing date OR before the mailing date of a first Office Action on the merits. No certification or fee is required.

Each non-English language reference was first cited in a corresponding foreign application search report or office action and its relevance discussed therein. A copy of the

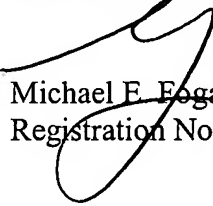
10/626,858

foreign search report or office action, together with an English language version thereof, is attached for the Examiner's information.

Please charge any shortage in fees due in connection with the filing of this paper, including extension of time fees, to Deposit Account 500417 and please credit any excess fees to such deposit account.

Respectfully submitted,

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SHEET 1 OF 1

INFORMATION DISCLOSURE CITATION IN AN APPLICATION (PTO-1449)				ATTY. DOCKET NO. 55071-267		SERIAL NO. 10/626,858	
				APPLICANT Stephen D. HSU, et al.			
				FILING DATE July 25, 2003		GROUP	
U.S. PATENT DOCUMENTS							
EXAMINER'S INITIALS	CITE NO.	Document Number Number-Kind Code ² (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear		
		US 5,881,125	03/09/1999	Dao			
		US 6,625,802 B2	09/23/2003	Singh et al.			
		US 6,553,562 B2	04/22/2003	Capodieci et al.			
		US 2002/166107 A1	11/07/2002	Van Os Lodewijk			
		US					
		US					
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		US					
		US					
FOREIGN PATENT DOCUMENTS							
EXAMINER'S INITIALS	CITE NO.	Foreign Patent Document Country Codes-Number + -Kind Codes (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines Where Relevant Figures Appear	Translation	
						Yes	No
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)							
EXAMINER'S INITIALS	CITE NO.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.					
		HSU, Stephen D., et al. "65 nm Full-chip Implementation Using Double Dipole Lithography." Optical Microlithography XVI, Santa Clara, California, USA, February 2003, Proceedings of the SPIE- The International Society for Optical Engineering, pp. 215-231, XP 009024366, ISSN: 0277-786X					
		HSU, Stephen D., et al. "Dipole Decomposition Mask-design for full Chip Implementation at the 100nm Technology Node and Beyond." Proceedings of the SPIE, US, Volume 4691, pp. 476-490, XP 002261072, ISSN: 0277-786X					
		TORRES, J.A., et al. "Model Assisted Double Dipole Decomposition." Proceedings of the SPIE, Volume. 4691, pp. 407-417, XP 002257323 ISSN: 0277-786X					
		LIM, Chang-Moon., et al. "Intra-field CD Variation by Stray Light from Neighboring Field." Optical Microlithography XV, Santa Clara, California, USA, March 2002, Proceedings of the SPIE- The International Society for Optical Engineering, 2002, pp.1412-1420, XP 002268484, ISSN: 0277-786X					
EXAMINER				DATE CONSIDERED			

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

1 Applicant's unique citation designation number (optional). 2 Applicant is to place a check mark here if English language Translation is attached.